	Application No.	Applicant(s)		
Notice of Allowability	10/500.268	ANDO ET AL.		
	Examiner	Art Unit		
	Felisa C. Hiteshew	1722		
The MAILING DATE of this communication app. All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85; NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT R of the Office or upon petition by the applicant. See 37 CFR 1.313. 1. This communication is responsive to the amendment filed.	(OR REMAINS) CLOSED in to or other appropriate communal BIGHTS. This application is su and MPEP 1308.	his application. If not incluication will be mailed in du	ided e course. THIS	
	on November 13, 2006.			
2. The allowed claim(s) is/are <u>2,5,6,8-10 and 16-20</u> .				
 3. Acknowledgment is made of a claim for foreign priority unally all blue of the: a) All blue of the: b) Some* c) None of the: certified copies of the priority documents have certified copies of the priority documents have Copies of the certified copies of the priority documents have 	e been received. e been received in Application	No	cation from the	
International Bureau (PCT Rule 17.2(a)).	culterits have been received i	ii tiiis hational stage applic	Zation from the	
* Certified copies not received:			•	
Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONN THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.	of this communication to file a MENT of this application.	reply complying with the r	equirements	
 A SUBSTITUTE OATH OR DECLARATION must be subm INFORMAL PATENT APPLICATION (PTO-152) which give 	nitted. Note the attached EXAN es reason(s) why the oath or d	MINER'S AMENDMENT or leclaration is deficient.	NOTICE OF	
5. CORRECTED DRAWINGS (as "replacement sheets") mus	st be submitted.			
(a) \square including changes required by the Notice of Draftspers		PTO-948) attached		
1) 🗌 hereto or 2) 🔲 to Paper No./Mail Date				
(b) ☐ including changes required by the attached Examiner' Paper No./Mail Date				
Identifying indicia such as the application number (see 37 CFR 1 each sheet. Replacement sheet(s) should be labeled as such in t	.84(c)) should be written on the the header according to 37 CFR	drawings in the front (not the first that the first	ne back) of	
 DEPOSIT OF and/or INFORMATION about the depo attached Examiner's comment regarding REQUIREMENT 	SIT OF BIOLOGICAL MATER FOR THE DEPOSIT OF BIOL	RIAL must be submitted. OGICAL MATERIAL.	Note the	
Attachment(s)				
1. Notice of References Cited (PTO-892)		rmal Patent Application		
2. Notice of Draftperson's Patent Drawing Review (PTO-948)	6. ∐ Interview Sum Paper No./Mi	☐ Interview Summary (PTO-413), Paper No./Mail Date		
 Information Disclosure Statements (PTO/SB/08), Paper No./Mail Date 		mendment/Comment		
Examiner's Comment Regarding Requirement for Deposit of Biological Material	8. 🛭 Examiner's St	atement of Reasons for Al	lowance	
-	9. ☐ Other <u></u>	Selva C. Hiteshev Felisa C. Hiteshev Primary Examiner Art Unit: 1722		

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EXAMINER'S AMENDMENT

1. An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Gerald T. Shekleton on January 4, 2007.

The application has been amended as follows:

Please cancel claims 13 and 14.

- 1. Claims 2, 5,6,8-10 and 16-20 are allowed.
- 2. The following is a statement of reasons for the indication of allowable subject matter: The most relevant prior art references were those that were submitted by the applicants. However, they do not teach nor fairly suggest singularly or in any combination thereof a method for eliminating defects from single crystal silicon, in which single crystal silicon that has been manufactured by the CZ method and that has not undergone an oxidation treatment is subjected to an ultra high temperature heat treatment by being heated to an ultra high temperature in an oxygen gas atmosphere or an atmosphere containing oxygen gas, and then cooled, thereby eliminating any void defects present in the single crystal silicon, wherein void defects present in the single crystal silicon are eliminated by adjusting parameters comprising the initial oxygen concentration in the single crystal silicon, the oxygen partial pressure of the atmosphere during heating up to the ultra high temperature, the oxygen partial pressure of the

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atmosphere during the ultra high temperature heat treatment, and the temperature at which the ultra high temperature heat treatment is performed.

Any inquiry concerning this communication or earlier communications from the Examiner should be directed to Felisa Hiteshew whose telephone number is (571) 272-1463. The examiner can normally be reached on Mondays through Thursday from 5:30 AM to 4:00 PM with Fridays off.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Yogendra Gupta, can be reached on (571) 272-1316. The fax phone number for the organization where this application or proceeding is assigned is (571) 273-1463.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system. see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866- 217-9197 (toll-free).

Felisa C. Hiteshew Primary Examiner Art Unit 1722